

# Carbon Nanotube Composite Surfaces for Electrical Contact Interfaces

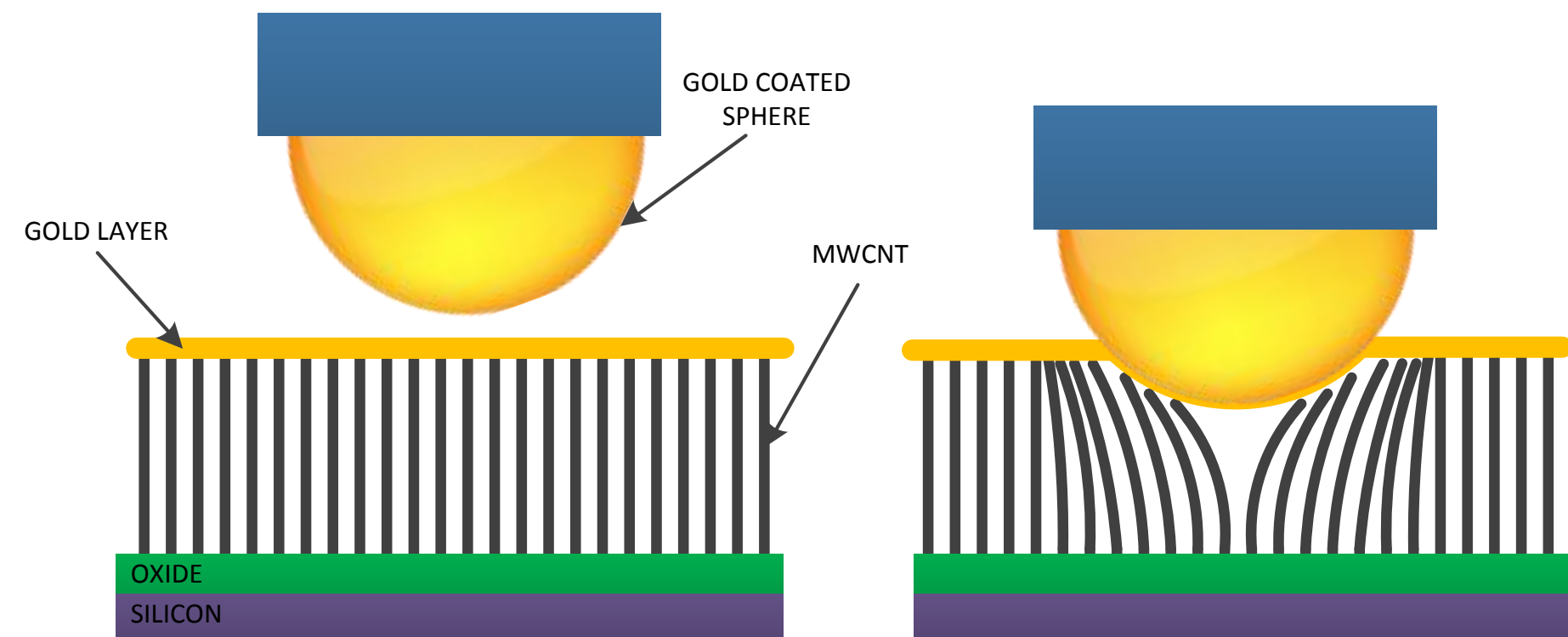
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## Problem Outline, Aims and Motivation

Material transfer between switching contact surfaces in MEMS relay switches causes device failure.

- Investigate CNT composite surfaces and develop robust mathematical models describing the contact and impact mechanics, contact resistance and switching performance of the surfaces.
- Develop CNT composite surfaces for integration into a MEMS relay device.
- Deliver prototype MEMS relay capable of switching over  $10^8$  cycles (with load conditions: 4 V > 10 mA).



Schematic illustrating switching mechanism between gold coated sphere and gold coated carbon nanotube composite surface. Electrical conduction is through the gold film; the MWCNT-forest is used for its mechanical properties.

## Modelling and Investigations

### Aims of Modelling

- Characterise and analyse the mechanics of the CNT array
- Characterise failure mechanisms of CNT array
- Create model for contact of and material transfer of Au-MWCNT and Au/MWCNT-Au/MWCNT
- Predict lifetimes of Au/MWCNT contact surfaces

### Fine Transfer Mechanism

Melting voltage:

$$\theta_m = \frac{V_c}{2\sqrt{L}} = 3200V_c (^{\circ}K)$$

Material transfer:

$$\Delta v = \frac{A_r t}{N}$$

Accounting for switching bouncing:

$$\Delta v = \frac{A_r t}{N \times n}$$

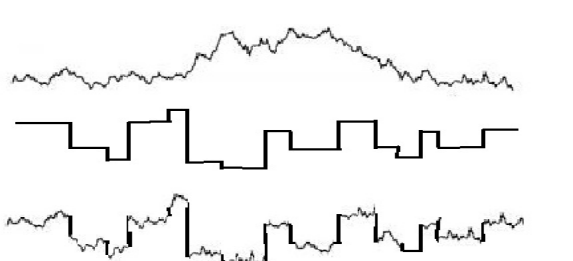
### Considerations

- Existing models exist in the forms of 1-D spring arrays, which do not describe buckling.
- Equation of motion for beams with damping:

$$\frac{\partial^2 u}{\partial t^2} + \frac{EI}{\rho A} \frac{\partial^4 u}{\partial x^4} - \frac{S}{\rho A} \frac{\partial^2 u}{\partial x^2} + \sigma(u) + 2 \left( \alpha_0 \frac{\partial u}{\partial t} - \alpha_1 \frac{\partial^3 u}{\partial t \partial x^2} + \alpha_2 \frac{\partial^2 u}{\partial t \partial x^4} \right) = 0.$$

### Plan

- Advance Euler's beam analysis to include CNT-CNT interactions and statistical model for entanglement.
- Statistical model required for the distribution and deformation of CNTs.



Modelling roughness of surface profile

- Au/MWCNT have increased surface roughness compared to Au contacts.
- Weierstrass' function is frequently used to describe surfaces (top line).
- Adding an additional term to the function (middle line) which describes the Gaussian nature of the height and width distributions of the CNT array creates an improved model.

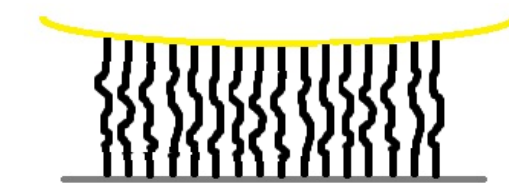
### Phase 1: Small Deformations: Elastic

- Elastic deformations
- Can be treated as array of 1-D springs or mass/springs
- Model required to fit force profile, which has hysteretic properties to describe foam-like nature of compression.



### Phase 2: Medium CNT Deformation: Interaction

- CNTs begin to deform.
- CNTs begin to interact with each other.
- Modelled as Euler's beam or a foam.



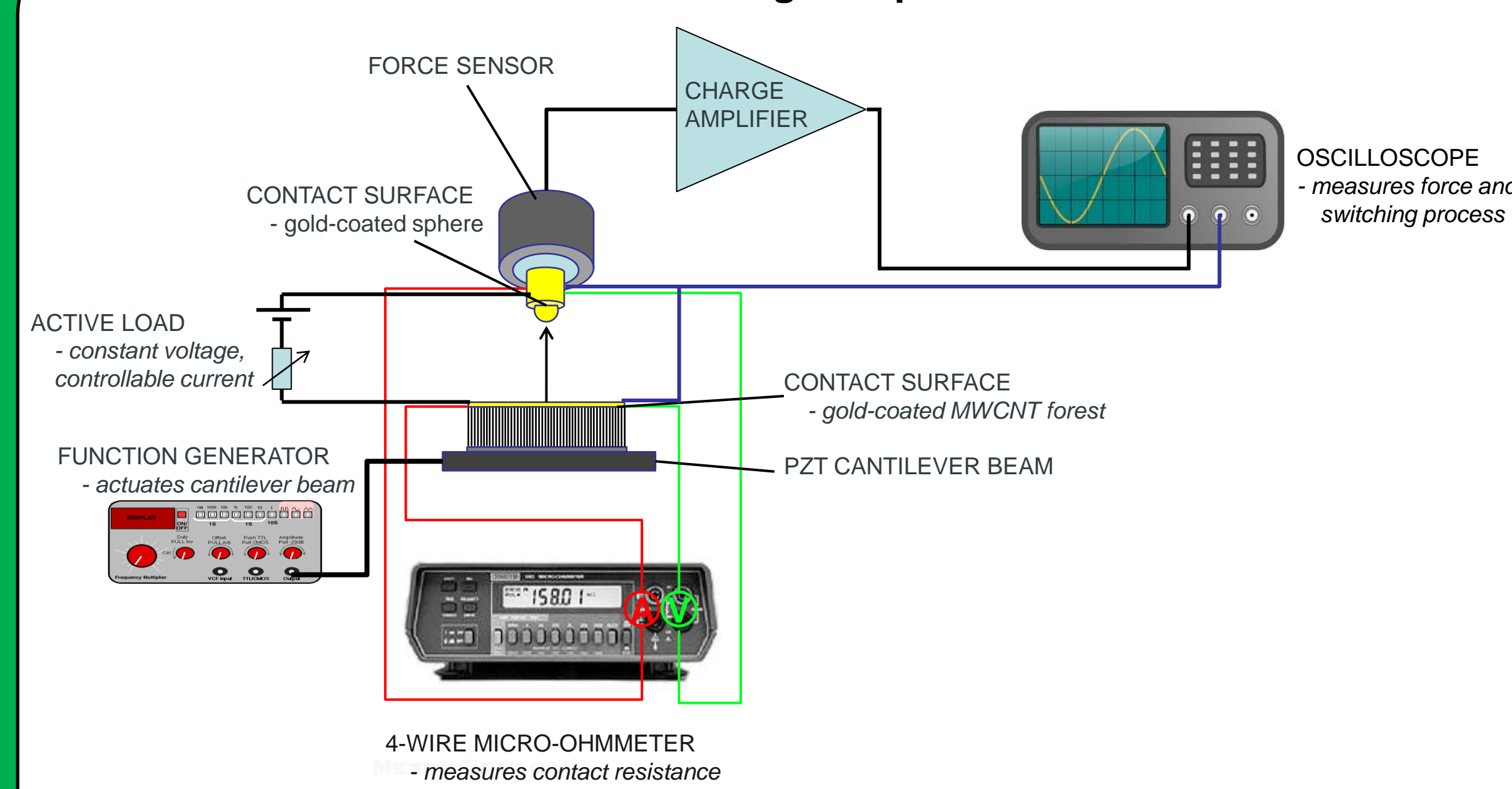
### Phase 3: Large CNT Deformation: Entanglement

- Requires additional terms to equation of motion to describe CNT-CNT interactions.
- Permanent deformation due to entanglement.



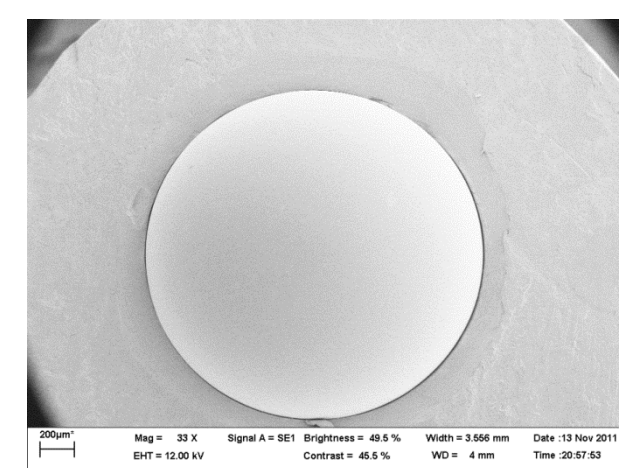
## Experimental Work

### Test Rig Setup

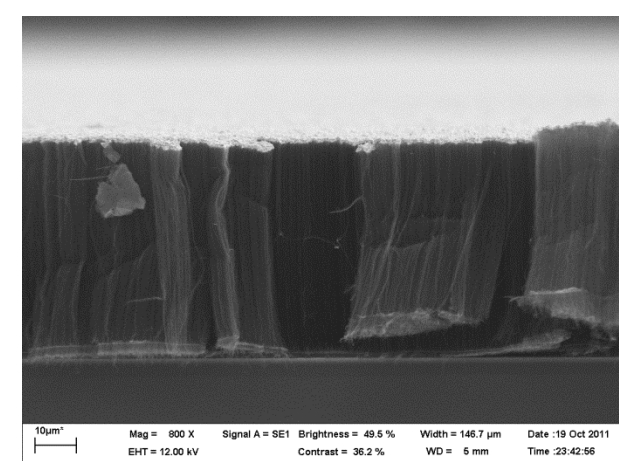


Schematic of experimental setup. A piezoelectric cantilever, on which a Au/MWCNT contact is mounted, is actuated by a function generator. The force applied is measured by a force sensor. The contact resistance is measured with a 4-wire ohmmeter. The voltage across the switching contacts is 4 V and the current is varied from 10 mA to 50 mA.

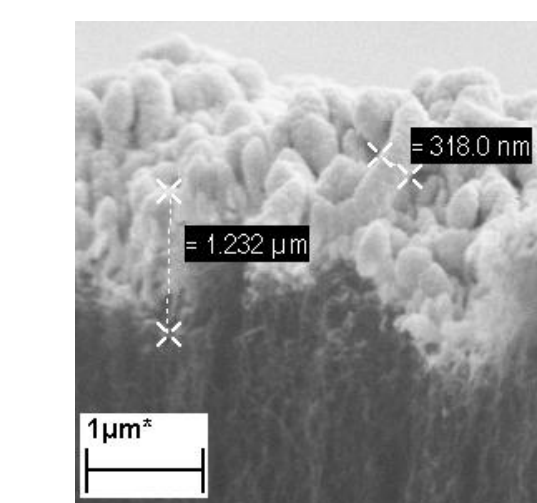
### SEM Images of Contact Before Failure



**Au-coated Stainless Steel Ball**  
500 nm of Au is sputtered onto the ball. The resulting surface is smooth.

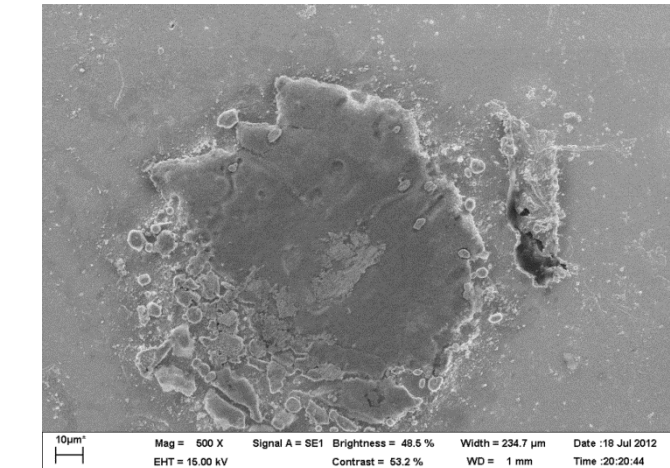


**Angled View of Au-Coated MWCNT Surface**  
MWCNT forests are grown using thermal CVD. Height varied by altering growth time.

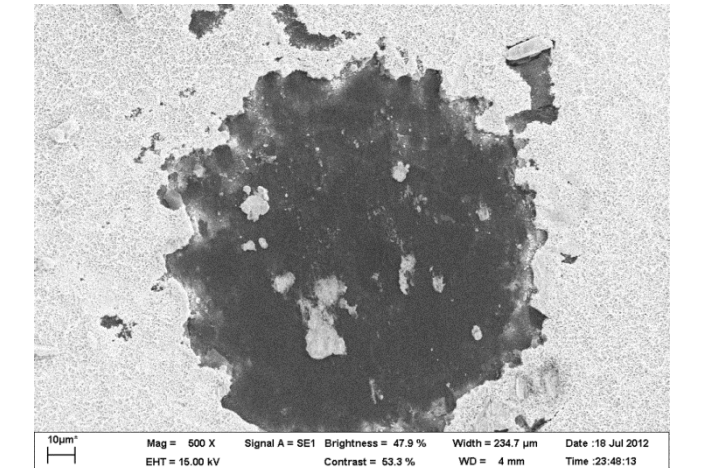


**Au-MWCNT Surface**  
500 nm of Au is sputtered onto the MWCNT forests.  
Surface roughness:  $R_a \approx 1200$  nm

### SEM Images of Contact Surfaces After Failure



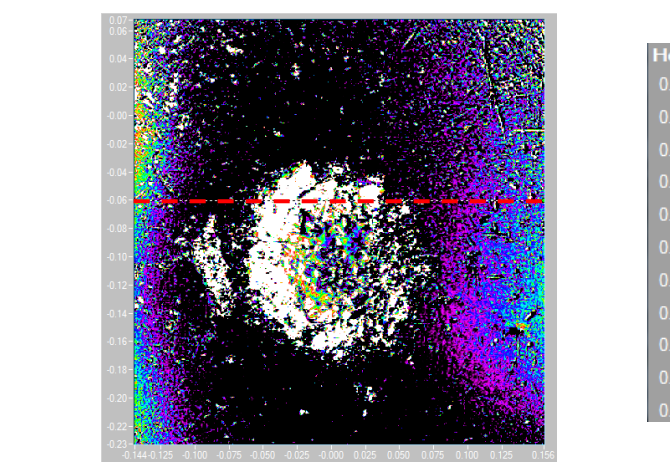
Au-coated stainless steel ball.



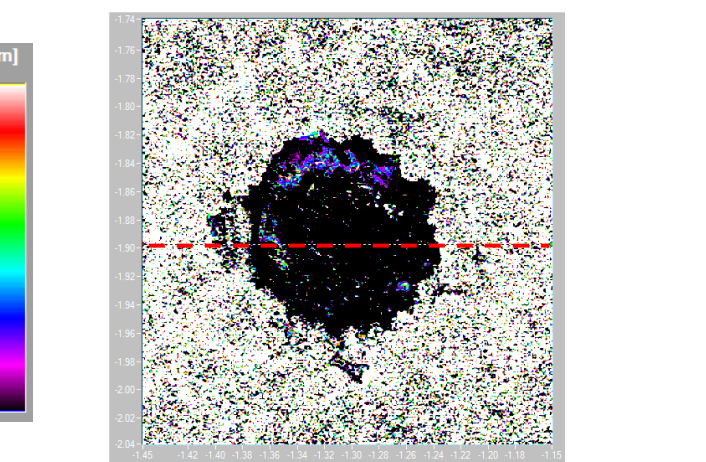
Au-coated MWCNT surface.

Load current: 50 mA  
Load voltage: 4 V  
CNT height: 30  $\mu$ m  
Cycles to failure:  $\sim 10^8$

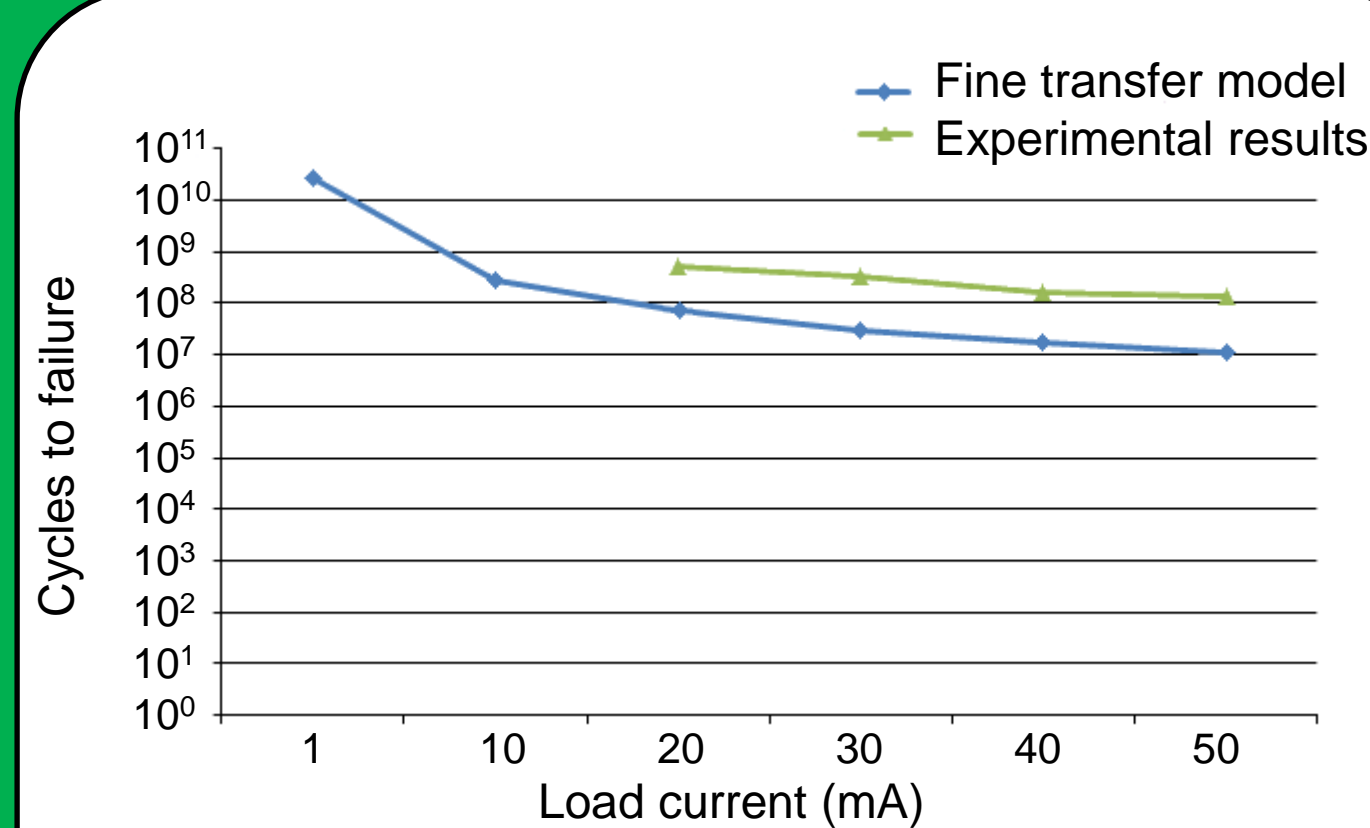
### Laser Scan of Contact Surfaces After Failure



Au-coated stainless steel ball.



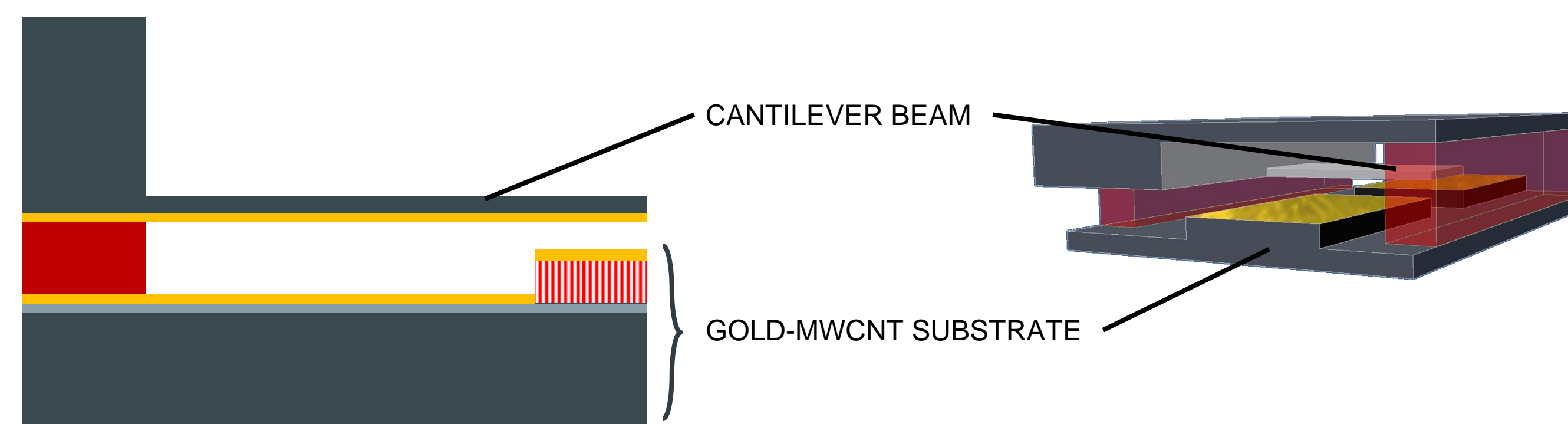
Au-coated MWCNT surface.



Graphs showing number of cycles until failure. CNT height and load voltage were constant at 30  $\mu$ m and 4 V respectively. Load current varied.

## MEMS Switch

Au-coated cantilever positioned above the Au-MWCNT composite surface, on which a transmission line strip is patterned.



## Why MEMS Switches?

Examples of alternative technologies:

PIN diodes, electromechanical relays and field effect transistors

Advantages of MEMS switches:

Very low power-consumption when in off state  
Very low on-resistance  
Small size

High cut-off frequency } these are particularly important for RF MEMS applications

Low insertion loss }  
Further to this, the ability to switch at high frequencies will aid the investigation into the switch failure mechanism.

## Conclusions

- The use of Au-MWCNT composite as surfaces for electrical contacts has shown an increase in contact lifetime.
- The fine transfer mechanism which contributes to contact failure has been described.
- Switching lifetimes in excess of  $10^8$  cycles have been demonstrated for hot switching conditions.
- A MEMS switch has been designed to enable high frequency testing of the Au-MWCNT surface.

## Future Work

- Investigate and computationally model the contact failure mechanisms.
- With current test rig evaluate the effect on lifetime of:
  - CNT forest height.
  - Load current.
  - Contact force.
- Fabricate the MEMS switch :
  - To provide experimental data.
  - To show feasibility of incorporating MWCNT into a MEMS switch.

## Acknowledgements

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## Industrial Engagement

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